

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Hans Wilfried Peter KOOPS
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Title: **PROCEDURE FOR ETCHING OF MATERIALS AT THE SURFACE
WITH FOCUSSED ELECTRON BEAM INDUCED CHEMICAL
REACTION AT SAID SURFACE**

Application Serial No. : 10/628,174

Filing Date: July 28, 2003

Assignee: NaWoTec GmbH

Priority claimed: October 16, 2002, European Patent No. 02 023 217.9

Docket: 8183

Examiner: Allan Olsen, Art Unit 1792

Date: May 28, 2008

Confirmation No. 5591 OK TO ENTER: /A.O./

AFTER-FINAL AMENDMENT AND INTERVIEW SUMMARY RECORD

OK TO ENTER: /A.O./

This amendment is in response to the Office Action mailed January 28, 2008.

Claims 1-41 and 43 are now canceled. Claims 42 and 44 were previously withdrawn but applicants respectfully request that they be rejoined upon the determination of allowable subject matter.

Claims 46, 63, 64, 65, 66, 67, and 68 have been amended. Claims 45-68 are in the application.

The Primary Examiner determined that claims 63-68 contain allowable subject